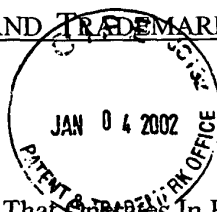
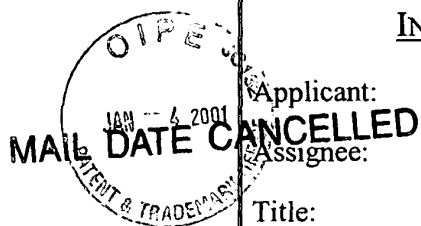


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant: James M. Holden
Assignee: Nanometrics Incorporated
Title: Configurable Metrology Device That Operates In Reflectance Mode, Transmittance Mode, Or Mixed Mode
Serial No.: 09/923,723
Filing Date: August 6, 2001
Examiner: Unknown
Group Art Unit: Unknown
Docket No.: M-9131 US

San Jose, California
October 17, 2001

COMMISSIONER FOR PATENTS
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying form PTO-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on October 17, 2001.

Michael J. Halbert 10-17-01
Attorney for Applicant Date of Signature

Respectfully submitted,

Michael J. Halbert

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U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					M-9131 US		09/923,723	
(Use several sheets if necessary)					Applicant			
					James M. Holden			
					Filing Date		Group	
					August 6, 2001		Unknown	

U.S. Patent Documents							
*Examiner Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,889,593	Mar. 30, 1999	Bareket	356	445	
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
	AQ	Harrison, D. et al., "Innovations in Lithography Metrology for Characterization of Phase-Shift Mask Materials" <i>SPIE</i> (2001) Pages 233-240.
	AR	"n&k Analyzer 1512RT", downloaded 9/25/01 from < http://www.nandk.com/1512rt.html >, n&k Technology, Inc. (2001).
	AS	

Examiner	Date Considered
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***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.